AMENDMENT TO THE CLAIMS

1. (currently amended): A method for automated focusing <u>of an electron image</u> in an electron imaging system, the method comprising:

selecting an area on which to focus and impinging an electron beam over the area;

monitoring an energy filter cut-off voltage during electron imaging of a substrate;

measuring an average intensity of detected electrons over a range of filter bias voltages so as to determine an energy filter cut-off voltage; and

adjusting a stage bias voltage setting an operating condition of the electron imaging system in negative correspondence with based on the energy-filter cut-off voltage so as to maintain a focus of the electron image put the electron image into focus without needing to determine a sharpness or contrast of the electron image.

- 2. (currently amended): The method of claim 1, wherein the operating condition comprises a stage bias voltage, and wherein, in order to maintain the focus of the electron image, the stage bias voltage is increased when the energy-filter cut-off voltage decreases, and the stage bias voltage is decreased when the energy-filter cut-off voltage increases.
- 3. (currently amended): The method of claim 1, wherein the operating condition comprises a stage bias voltage, and wherein, in order to maintain the focus of the electron image, the stage bias voltage is increased by a same voltage amount as the energy-filter cut-off voltage decreases, and the stage bias voltage is

Docket No. 10011.002300 (P1240)

Response To Final Office Action

August 2, 2005

decreased by a same voltage amount as the energy-filter cut-off voltage

increases.

4. (currently amended): The method of claim 1, wherein, instead of adjusting the

stage bias voltage, wherein the operating condition comprises a strength of an

objective lens is adjusted.

5. (currently amended): The method of claim 1, wherein, instead of adjusting the

stage bias voltage, wherein the operating condition comprises a strength of an

extraction field is adjusted.

6. (currently amended): The method of claim 1, wherein, instead of adjusting the

stage bias voltage, a strength of a source voltage level is adjusted.

7. (currently amended): The method of claim 1, wherein said adjusting putting

the electron beam in focus without needing to determine the sharpness or

contrast of the electron image provides for rough focusing of the electron image.

and further comprising using a contrast-based focusing procedure for fine

focusing of the electron image.

Claims 8-10. (canceled):

11. (currently amended): A system for automated focusing of an electron image

in an electron beam inspection apparatus, the apparatus including an

autofocusing means that comprises: system comprising:

means for selecting an area on which to focus and for impinging an

electron beam over the area;

Page 3 of 9

August 2, 2005

means for monitoring an energy filter cut-off voltage during electron

imaging of a substrate measuring an average intensity of detected electrons over

a range of filter bias voltages so as to determine an energy filter cut-off voltage;

and

control means for adjusting configured to set a stage bias voltage of the

electron beam inspection apparatus in negative correspondence with based on

the energy-filter cut-off voltage so as to maintain a focus of an electron-image put

the electron image into focus without needing to determine a sharpness or

contrast of the electron image.

Claims 12-21. (canceled)

22. (currently amended) The apparatus system of claim 11, wherein, in order to

maintain the focus of the electron image, the control means is further configured

to increase the stage bias voltage is increased when the energy-filter cut-off

voltage decreases, and to decrease the stage bias voltage is decreased when

the energy-filter cut-off voltage increases.

23. (currently amended) The apparatus system of claim 11, wherein, in order to

maintain the focus of the electron image, the control means is further configured

to increase the stage bias voltage is increased by a same voltage amount as the

energy-filter cut-off voltage decreases, and to decrease the stage bias voltage is

decreased by a same voltage amount as the energy-filter cut-off voltage

increases.

Page 4 of 9